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Shunji Goto
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Ali M. Khounsary
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Introduction

This volume contains papers presented at the conference on "Advances in X-Ray/EUV Optics and Components X," which was held in San Diego, California, United States on 11–12 August 2015 as part of the SPIE 2015 International Symposium on Optics + Photonics.

The conference was composed of five oral sessions: Multilayers, Focusing, Optics Development and Fabrication, Instrumentation and Imaging, and Optics for Coherent Sources. The final session was held jointly with the conference on "X-ray Lasers and Coherent X-Ray Sources: Development and Application XI."

The focus of the conference was technological developments in X-ray/EUV optics for synchrotron and FEL beamlines. Presentations covered a wide spectrum, from vacuum ultra violet to hard X-rays. Topics related to X-ray lasers, coherent X-ray sources, laboratory-based X-ray sources, and X-ray imaging were presented in independent conferences at the same symposium.

Scheduled for nearly one and a half days of oral presentations with an accompanying evening poster session, the conference was lively and well attended. We would like to thank the authors, speakers, session and joint session chairs, program committee members, the conference participants for their contributions, and the SPIE staff for their help in organizing the conference.

Shunji Goto
Christian Morawe
Ali M. Khounsary